DERWENT-ACC-NO: 1996-214884

DEFWENT-WEEK: 200045

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TITLE: Magneto electric conversion element - in which

protection layer

comprising resin and stress relieving material surrounds

magneto resistance

effect generation layers which are formed on magnetic

substance substrate

PATENT-ASSIGNEE: MURATA MFG CO LTD[MURA]

PRIORITY-DATA: 1994JP-0213756 (September 7, 1994)

PATENT-FAMILY:

FUB-NO PUB-DATE LANGUAGE

FAGES MAIN-IPC

JF 3085100 B2 September 4, 2000 N/A

005 H01L 043/08

JP 08078755 A March 22, 1996 N/A

005 H01L 043/08

APPLICATION-DATA:

FUB-NO APPL-DESCRIPTOR APPL-NO

APPL-DATE

JF 3085100B2 N/A 1994JP-0213756

September 7, 1994

JP 3085100B2 Previous Publ. JP 8078755

N/A

JP 08078755A N/A 1994JP-0213756

September 7, 1994

INT-CL (IFC): G01R033/09; H01L043/08

ABSTRACTED-PUB-NO: JP 08078755A

BASIC-ABSTRACT: The magneto electric conversion element

(10) has a magnetic

substance substrate (1). Above this substrate, multiple

magneto resistance

effect generation layers (2) are formed.

These layers are surrounded by a protection layer (3a)

which consists of a

mixture of resin and stress relieving material. The

magnetic substance substrate is thus bonded to this protection layer.

ADVANTAGE - Reduces constraint during pattern designing process.

CHOSEN-DRAWING: Dwg.1/7

TITLE-TERMS:

MAGNETO ELECTRIC CONVERT ELEMENT PROTECT LAYER COMPRISE
RESIN STRESS RELIEVE
MATERIAL SURROUND MAGNETO RESISTANCE EFFECT GENERATE LAYER
FORMING MAGNETIC
SUBSTANCE SUBSTRATE

DERWENT-CLASS: S01 U12

EPI-CODES: S01-E01B; U12-B01B;

SECONDARY-ACC-NO:

Non-CPI Secondary Accession Numbers: N1996-180309

DERWENT-ACC-NO: 1999-085809

DERWENT-WEEK: 199911

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TITLE: Silicon radder (sic) type photopolymer composite,

and process for

patterning - for passivation layer for semiconductor appts.

FATENT-ASSIGNEE: MITSUBISHI ELECTRIC CORP[MITQ]

FRIORITY-DATA: 1997JP-0133602 (May 23, 1997)

FATENT-FAMILY:

FUB-NO PUB-DATE LANGUAGE

FAGES MAIN-IPC

JP 10319597 A December 4, 1998 N/A

018 G03F 007/075

APPLICATION-DATA:

FUB-NO APPL-DESCRIPTOR APPL-NO

APPL-DATE

JF10319597A N/A 1997JP-0133602

May 23, 1997

INT-CL (IPC): C08F002/48; C08F290/14; C08L083/04;

G03F007/004 ;

G03F007/028; G03F007/075; H01L021/312

ABSTFACTED-PUB-NO: JF10319597A

BASIC-ABSTRACT: Claimed silicon radder type photopolymer

composite comprises a

silicon radder resin of the formula (1), and a

photocrosslinking agent or a photopolymerisation initiator.

Formula (1)-p

F.1, F.2 = H, aryl, alkyl, unsaturated group;

E3, E4, R5, R6 = H, aryl, alkyl, trialkylsilyl; unsaturated group; at least 1

wt. of the total of R1 - R6 is a light-sensitive group; n = integer).

Also claimed is the patterning process comprising (a)

forming the layer of the composite on a base plate, (b) heating the composite layer at a temperature at least 5 deg. C lower than the m.pt. of any of the component, (c) exposing the layer through a photomask and (d) developing the exposed layer.

Further claimed is the semiconductor apparatus comprising a base plate and the photopolymer layer.

USE - The composite is used for providing the passivation layer for semiconductor apparatus.

ALVANTAGE - The passivation layer has good stability, and is formed by a rapid and simple patterning process.

CHOSEN-DRAWING: Dwg.0/1

TITLE-TEPMS:

SILICON TYPE PHOTOPOLYMERISE COMPOSITE PROCESS PATTERN FASSIVATION LAYER SEMICONDUCTOR APPARATUS

DERWENT-CLASS: A26 A89 G06 L03 P84 U11

CFI-CODES: A06-A00E4; A08-C01; A08-D01; A11-C02B; A12-E07C; A12-L02B2; G06-E02; G06-F03D; G06-G17; G06-G18; L04-C06;

EFI-CODES: U11-C05A; U11-C20;

ENHANCED-POLYMER-INDEXING:

Folymer Index [1.1]

018 ; D11 D10 D12 D18*R D51*R F81 F83 F86 F87 ; P1445*R F81 Si 4A

; L9999 L2391 ; L9999 L2073 ; M9999 M2073 ; S9999 S1627 S1605 ;

H0179 ; H0282

Filymer Index [1.2]

018; ND01; ND04; B9999 B4988*R B4977 B4740; K9847*R K9790;

K9869 K9847 K9790 ; B9999 B5243*R B4740 ; B9999 B5094 E4977 B4740

; B9999 B3532 B3372 ; Q9999 Q8673*R Q8606 ; Q9999 Q7476

11/21/2002, EAST Version: 1.03.0002

Q7330 ;
 N9999 N7147 N7034 N7023 ; Q9999 Q7170 Q7158 Q7114 ;
K9585 K9483
Polymer Index [1.3]
 018 ; D01 D11 D10 D07 D25 D22 D33 D79 D43 D50 D93 F23 ;
D01 D11
 D10 D19 D18 D23 D22 D32 D76 D41 D93 F23 F00 ; A999 A179
A157
Polymer Index [1.4]
 018 ; D01 ; R01056 G2595 D01 D11 D10 D50 D63 D86 F41
F89 ; A999
 A475

SECONDARY-ACC-NO:

CFI Secondary Accession Numbers: C1999-025938
Non-CPI Secondary Accession Numbers: N1999-062203